Full Face Erosion Planar Cathodes as a Low Cost “Cylindrical Rotatable” R&D Tool

Alena Vetushka, Victor Bellido-Gonzalez, Heqing Li, Frank Papa

Gencoa Ltd

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Oral Presentation Session
Grand Ballroom G

Tuesday - April 28, 2015 – 2:30pm-3:30pm
**Industrial**

**Cylindrical Rotatable cathodes**

**ROTATABLE CATHODE**

- Static plasma with dynamic rotating target

Cost of target is expensive

Stationary plasma with target rotation

Very high cost of target inventory, prohibitive for many R&D labs
Mainly planar circular cathodes

Moving magnets behind the target

Clean target surface due to plasma rotation

Static target with dynamic rotating plasma

Lower cost target inventory

But can the cathodes correctly simulate the industrial processes?
plasma movement
Thank You

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